Supplementary Information

Simple Modification to Allow High-Efficiency and High-Resolution Multi-Material 3D-Printing Fabrication of Microfluidic Devices

Reverson Fernandes Quero¹, Dosil Pereira de Jesus^{1,2}, José Alberto Fracassi da Silva^{1,2,*}

¹Institute of Chemistry, University of Campinas, UNICAMP, P.O. Box 6154, 13083-970 Campinas, SP, Brazil ²Instituto Nacional de Ciência e Tecnologia de Bioanalítica (INCTBio), Campinas, SP, Brazil

*Corresponding author: fracassi@unicamp.br

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Table SI1 – Characteristics of the DLP projector (manufacturer information).

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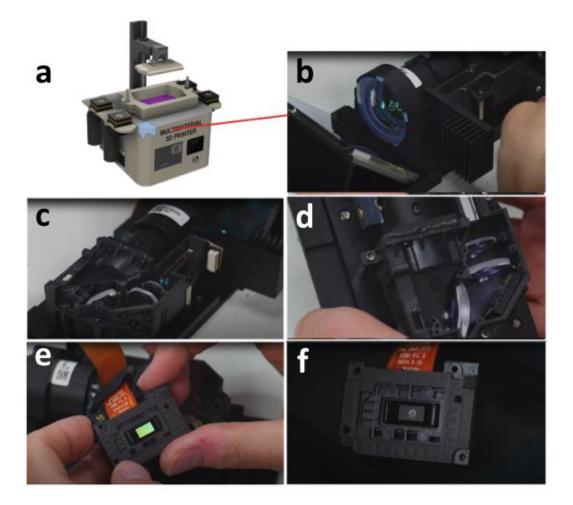


Figure SI1 - Position of the DLP projector^{*} and details of its construction. (a) Position on the printer case. (b) Projection len and mirror. (c-d) Details of the internal optics. (e-f) Detail of the digital micromirror device (DMD). In (f) is projected the logotype of the State University of Campinas (UNICAMP).

- 1. Hight resolution 3840*2160
- 2. Instant LED on/off.
- 3. Dedicated for UV Lithography application.
- 4. Excellent optical performance
- 5. Easy installation to multiple unit integration
- 6.Common software platform : PDC05/PDC06/PDC07

(Manufacturer information)

^{*}PDC07 light engine inside DLP 660te UHD DMD chipset, which is well suited for professional industrial 3D printer, the kit projection optical system have been optimized from 385nm to 405nm wavelength especially; use all glass lens and metallic body material to meet the industrial device requirement; also, several type of projection lens optionally could match with the projection optical system to meet the different printing image; Developers can easily manage the light power, create, store, through an easy-to-use graphical user interface from development platform. Features

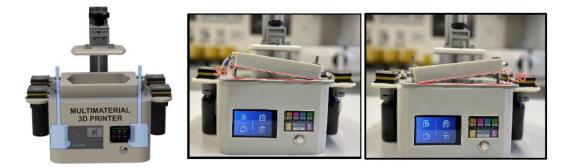


Figure SI2 - Position of the two stepper motors and vat inclination system.

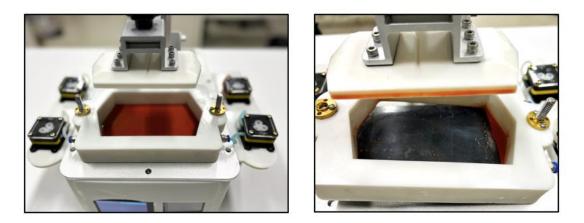


Figure SI3 - Resin being withdraw back to the source reservoir.



Figure SI4 - Vat design and printed part.

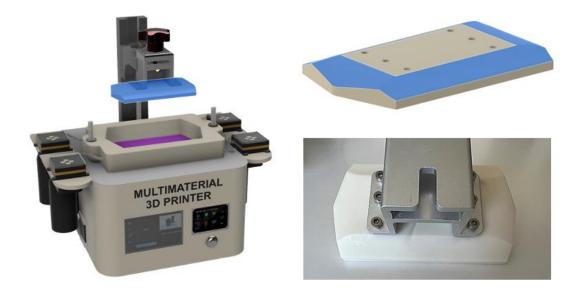


Figure SI5 – Print platform design with chamfered perimeter design for easy resin cleaning when changing materials.

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Figure SI6 – G-code generated for multi-material printing of the object using the NanoDLP software.

G-Code UNICAMP GEM03 *G-Code - Bootup :** **G-Code - Start Of Print:** \$X ; Unlock GRBL in case we're in an alarm state G90 ; Put GRBL in absolute mode \$H ; Home GRBL so we can start from a known place G4 P0.1 ; SolidRay movement sync [[WaitForDoneMessage]] ; Wait done message G92 X0 Y0 Z0 ; Set our new homed position as the origin [[PositionSet 0]] ; Set the current position as 0 in NanoDLP **G-Code - Before Each Layer:** G01 Z[[LaverPosition]] F100 ; Move to the correct laver height G4 P0.1 ; SolidRay movement sync [[WaitForDoneMessage]] ; Wait done message [[PositionSet [[LayerPosition]]]] ; Save the current position in NanoDLP *G-Code - After XX Layer:** [[Delay 1]] ; Wait 1 second for the resin to "settle" G01 Z{[[LayerPosition]] + [[ZLiftDistance]]} F100 ; Indicate the position that the platform must go up to change material G4 P0.1 ; Here must be added the code for material exchange [[WaitForDoneMessage]] ; Wait done message. You can put a message on the panel warning the change of material or a sound beep. [[Delay 120]]; Wait 120 seconds. Put the time for material exchange for the resin. [PositionChange [[ZLiftDistance]]]]; Indicate the position that the platform must lower to change material. *G-Code - End Of Print:** \$X ; Unlock GRBL just in case G01 Z0 F100 ; Bring the platform above the resin level *G-Code - Resume Print:** \$X ; Unlock GRBL in case we're in an alarm state G90 ; Put positioning in absolute mode G92 Z[[CurrentPosition]] Y0 X0 ; System crashed so we need to recover current position from NanoDLP and set it in GRBL G1 Z[[LayerPosition]] F100; Move to layer position G4 P0.1 ; SolidRay movement sync [[WaitForDoneMessage]] ; Wait done message

Figure SI7 - Manual editing of G-code using Monkeyprint software as controller.

Software, Firmware and files: LINK DRIVE

G-Codes on-line editor: LINK GITHUB

Simple Modification to Allow High-Efficiency and High-Resolution Multi-Material 3D-Printing Fabrication of Microfluidic Devices

Parts list for adaptation in Nova3D Bene6 Printer 2021 version



TFT Display Touch Panel Screen Module



32Bit 168Mhz F407 Control Board



2pcs Stepper Moto Nema 17



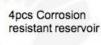
1 Stepper Motor Controller DM556S



4pcs Peristaltic Pump



3m PTFE Tube ID 2mm OD 4mm



4pcs Connector Fitting PC4-M5



1pc FEP Film 130 x 70 mm



2pcs Stainless Steel Trapezoidal Rod T8 Lead



2pcs Flexible Coupler T8 4mm



Anti-backlash Spring Loaded Nut

2 pcsTrapezoidal

Figure SI8 – Parts list for adaptation of Nova3D Bene6 printer 2021 version.



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Parts list for adaptation in Anycubic DLP D2 Printer 2022 version



TFT Display Touch Panel Screen Module



32Bit 168Mhz F407 Control Board



2pcs Stepper Moto Nema 17



1pc Stepper Motor Controller DM556S



4pcs Peristaltic Pump

3m PTFE Tube ID 2mm OD 4mm

4pcs Corrosion resistant reservoir

4pcs Connector Fitting PC4-M5



1pcFEP Film 150 x 80 mm



2pcs Stainless Steel Trapezoidal Rod T8 Lead



2pcs Flexible Coupler T84mm



2 pcsTrapezoidal Anti-backlash Spring Loaded Nut

Figure SI9 – Parts list for adaptation of Anycubic DLP D2 printer 2022 version.

 Table SI1 – Characteristics of the DLP projector (manufacturer information).

Model

NO	Production name	Printing Resolution	Image@Work distance	Optical distortion	wavelength
1	PDC07-30	28-35um	115.2*64.8@158	0.10%	405/385

Specifications

8	I			
isplay technique TI DLP 0.66-inch 4K UHD DMD				
Resolution	3840*2160 XPR			
Light source	LED UV405/385nm			
Light channel	Single channel			
Optical power	5.5W@120W			
Offset	Without offset			
Contrast	1200:1			
Uniformity	>92%			
Power supply	AC110V~240V, 50/60HZ, DC12V/7A			
Total power	<120W			
Dimension	L325*W272*H160mm			
	DCIN			
interface	HDMI-TYPEA			
	miniUSB			

Resin	Composition/Modification	Feature/application	Viscosity (cps at 25 °C)	Tensile strength (MPa)
GEM 1 ^a	See note below	Rigid-clear	176 ± 30	38 ± 8
GEM C1 ^a	PEDOT:PSS	Conductive	484 ± 30	54 ± 7
GEM C2 ^a	3D-ADD CuEK1	Conductive	375 ± 40	48 ± 12
GEM 2 ^a	GEM 1 with blue fluorescent pigment XUK473/3019	Fluorescent	198 ± 20	42 ± 8
GEM 3 ^a	GEM 1 with fluorophore pigment TEXWUJJJ	Phosphorescent	234 ± 30	40 ± 10
Siraya Fast	Pigmented with dyes	Colored resins	100 ^b	33 ^b
3Dresyn IM-HT- WS	Commercial - unmodified	Water-soluble	<100 b	>40 ^b
Siraya Blu	Commercial - unmodified	Rigid-clear	700 ^b	50 ^b
Siraya Tenacious	Commercial - unmodified	Flexible	500 ^b	24 ^b

Table SI2 - Additional data on the resins used

^a Manufactured resin: GEM 1: Oligomer: 39.8% Ebecryl 8210 and 39.8% Sartomer SR 494. Reactive diluente: 19.8%, genomer 1122. Photoinitiator: 0.4%, 2,4,6 Trimethylbenzoyl-diphenyl-phosphineoxide (TPO) and UV blocker, 0.2 %: 2,2'-(2,5-thiophenediyl)bis(5-tert-butylbenzoxazole) (OB+).

GEM C1: GEM 1 with poly(3,4-Ethylenedioxythiophene)-polystyrenesulfonate (PEDOT:PSS).

GEM C2: GEM 1 with 3D-ADD CuEK1.

^b Provided by the manufacturer.